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**Examiner: David B. Thomas**

OCT 01 2002

TECHNOLOGY CENTER R3700

**CERTIFICATE UNDER 37 CFR 1.10**

I hereby certify that this correspondence and the documents referred to as attached therein are being deposited on September 25, 2002 with the United States Postal Service in an envelope as "Express Mail Post Office to Addressee," mailing label No. EV186612760US addressed to: BOX RCE Commissioner for Patents, Washington, D.C. 20231.

Date 9/25/02 Signature Keith J. Parks

Prior to continued examination, please enter the following amendments.

**Please cancel claims 1-4 and 14-20, and amend the claims as follows:**

1. (Cancelled) A chemical mechanical polishing pad having a plurality of reliefs in a main polishing surface for determining wear of the pad, wherein the reliefs are disposed in a predetermined pattern such that the wear of the pad is determinable as a function of pad radius.